

EAST - [10604190.wsp:1]

File View Edit Tools Window Help

☐ Drafts  
☐ BRS: 4 and spacer\$1  
☐ Pending  
☒ Active  
☐ L1: (1) ("6512273").PN.  
☐ L2: (1381) CMOS and nFET and pFET  
☐ L3: (4) 2 and ((compressive near stress) and (tensile near stress))  
☐ L4: (280) CMOS and ((compressive near stress) and (tensile near stress))  
☐ L5: (73) 4 and spacer\$1  
☐ Failed  
☐ Saved  
☐ Favorites  
☐ Tagged (0)  
☐ UDC  
☐ Queue  
☐ Trash

DBs: ☐ USPAT; ☐ US-PGPUB; ☐ EPC ☐ Plurals  
 Default operator: ☐ OR ☒ Highlight all hit terms initially

4 and spacer\$1

☒ BRS form ☐ IS&E form ☐ Image ☐ Text ☐ HTML

	U	I	Document ID	Issue Date	Pages	Title	Current OR	Current XRef
1	<input type="checkbox"/>	<input type="checkbox"/>	US 20040126990 A1	20040701	25	Semiconductor device having STI without divot its manufacture	438/435	438/424
2	<input type="checkbox"/>	<input type="checkbox"/>	US 20040115897 A1	20040617	19	Manufacture of semiconductor device having STI and semiconductor device	438/424	438/400
3	<input type="checkbox"/>	<input type="checkbox"/>	US 20040115888 A1	20040617	11	[METHOD FOR FABRICATING LOCALLY STRAINED CHANNEL ]	438/285	438/305
4	<input type="checkbox"/>	<input type="checkbox"/>	US 20040108599 A1	20040610	39	Wiring material, semiconductor device provided with a wiring using the wiring	257/763	
5	<input type="checkbox"/>	<input type="checkbox"/>	US 20040104405 A1	20040603	8	Novel CMOS device	257/199	
6	<input type="checkbox"/>	<input type="checkbox"/>	US 20040100518 A1	20040527	616	Inkjet printhead with short nozzle	347/20	
7	<input type="checkbox"/>	<input type="checkbox"/>	US 20040099903 A1	20040527	11	Strained-channel multiple-gate transistor	257/317	
8	<input type="checkbox"/>	<input type="checkbox"/>	US 20040094812 A1	20040520	7	Metal gate engineering for surface p-channel devices	257/411	257/E21.204; 257/E21.637;
9	<input type="checkbox"/>	<input type="checkbox"/>	US 20040079952 A1	20040429	55	Semiconductor device and method of fabricating the same	257/81	257/E21.413; 257/E21.414;
10	<input type="checkbox"/>	<input type="checkbox"/>	US 20040063300 A1	20040401	17	Shallow trench filled with two or more dielectrics for isolation and coupling or for	438/425	
11	<input type="checkbox"/>	<input type="checkbox"/>	US 20040026765 A1	20040212	20	Semiconductor devices having strained dual channel layers	257/616	257/E21.448; 257/E21.633;